Journal Name: Physical Science International Journal
Manuscript Number: Ms_PSIJ_33788
Title of the Manuscript: Deposition of Silicon Films from Liquid Cyclopentasilane Precursors Using High Pressure Spray System
Type of the Article

General guideline for Peer Review process:
This journal’s peer review policy states that **NO** manuscript should be rejected only on the basis of ‘**lack of Novelty**’, provided the manuscript is scientifically robust and technically sound.
To know the complete guideline for Peer Review process, reviewers are requested to visit this link:

(http://www.sciencedomain.org/page.php?id=sdn-general-editorial-policy#Peer-Review-Guideline)
### PART 1: Review Comments

<table>
<thead>
<tr>
<th>Compulsory REVISION comments</th>
<th>Author's comment (if agreed with reviewer, correct the manuscript and highlight that part in the manuscript. It is mandatory that authors should write his/her feedback here)</th>
</tr>
</thead>
<tbody>
<tr>
<td>Author(s) should correct the mistakes in writing the chemical formula of cyclopentasilane and cyclohexasilane as written in the introduction. The following refs. were not cited in the text of the article: 13, 20. Also, refs. 21 – 38 were not reviewed. Why?</td>
<td></td>
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